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AMENDMENTS TO THE CLAIMS:

1. (Currently Amended) A transparent oxide electrode film having indium oxide containing

titanium as its main component, wherein tin is absent, and wherein indium in said indium oxide

is substituted with titanium at a titanium/indium atomic ratio between 0.003 and 0.120, said

indium oxide is crystalline, and the resistivity of said transparent oxide electrode film is up to 5.7

x 10<sup>-4</sup> Ωcm.

2. (Original) A transparent oxide electrode film according to claim 1, wherein said

titanium/indium atomic ratio is between 0.003 and 0.050, and the resistivity of said transparent

oxide electrode film is up to  $4.0 \times 10^{-4} \Omega$ cm.

3. (Previously Presented) A transparent oxide electrode film according to claim 1, wherein the

average light transmittance for wavelengths between 1000 nm and 1400 nm is at least 60%.

4. (Previously Presented) A transparent oxide electrode film according to claim 1, wherein the

carrier electron concentration given by Hall effect measurement is up to 5.5 x  $10^{20} \ \text{cm}^{-3}$ .

5. (Original) A transparent oxide electrode film according to claim 4, wherein the carrier electron

concentration given by Hall effect measurement is up to  $4.0 \times 10^{20} \text{ cm}^{-3}$ .

6. (Previously Presented) A transparent oxide electrode film according to claim 1, wherein the

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carrier electron mobility given by Hall effect measurement is at least 40 cm<sup>2</sup>/Vsec.

7. (Original) A transparent oxide electrode film according to claim 6, wherein the carrier electron

mobility given by Hall effect measurement is at least 60 cm<sup>2</sup>/Vsec.

8. (Original) A transparent oxide electrode film according to claim 6, wherein he carrier electron

mobility given by Hall effect measurement is at least 70 cm<sup>2</sup>/Vsec.

9. (Withdrawn) A transparent oxide electrode film having indium oxide containing titanium and

tungsten as its main component, wherein indium in said indium oxide is substituted with titanium

and tungsten at a ratio which when the titanium/indium atomic ratio is deemed x and the

tungsten/indium atomic ratio is deemed y, satisfies an equation (1),  $0.019-1.90x \le v \le 0.034-$ 

0.28x (1) and wherein said indium oxide is crystalline, and the resistivity is up to  $5.7 \times 10^{-4} \, \Omega cm$ .

10. (Withdrawn) A transparent oxide electrode film according to claim 9, wherein when the

titanium/indium atomic ratio is deemed x and the tungsten/indium atomic ratio is deemed y, said

ratio satisfies an equation (2) 0.019-1.27x  $\leq y \leq 0.034$ -0.68x (2) and wherein said resistivity is

up to  $3.8 \times 10^{-4} \Omega$ cm.

11. (Withdrawn) A transparent oxide electrode film according to claim 9, wherein the average

light transmittance for wavelengths between 1000 nm and 1400 nm is at least 60%.

12. (Withdrawn) A transparent oxide electrode film according to claim 9, wherein the carrier

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electron concentration given by Hall effect measurement is up to 5.5 x  $10^{20} \ cm^{-3}$ .

13. (Withdrawn) A transparent oxide electrode film according to claim 12, wherein the carrier

electron concentration given by Hall effect measurement is up to 4.0 x  $10^{20} \ cm^{-3}$ .

14. (Withdrawn) A transparent oxide electrode film according to claim 9, wherein the carrier

electron mobility given by Hall effect measurement is at least 40 cm<sup>2</sup>/Vsec.

15. (Withdrawn) A transparent oxide electrode film according to claim 14, wherein the carrier

electron mobility given by Hall effect measurement is at least 60 cm<sup>2</sup>/Vsec.

16. (Withdrawn) A transparent oxide electrode film according to claim 15, wherein the carrier

electron mobility given by Hall effect measurement is at least 70 cm<sup>2</sup>/Vsec.

17. (Withdrawn) A manufacturing method for a transparent oxide electrode film according to

claim 1, wherein said transparent oxide electrode film is deposited by a sputtering method using

either a sputtering target manufactured from an oxide sintered body for which the constituent

elements are substantially indium, titanium and oxygen, or a sputtering target manufactured from

an oxide sintered body for which the constituent elements are substantially indium, titanium,

tungsten and oxygen, at a substrate temperature of at least 100° C., using a mixed gas of argon

and oxygen containing at least 0.25% oxygen as the sputtering gas.

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18. (Original) A transparent electroconductive base material, wherein a transparent oxide

electrode film according to claim 1 is formed on a transparent substrate.

19. (Original) A transparent electroconductive base material of claim 18, wherein the average

light transmittance in the wave length range from 1000 nm to 1400 nm is at least 60%, and

wherein the surface resistance is up to 30  $\Omega/\Box$ .

20. (Withdrawn) A solar cell, which uses a transparent oxide electrode film according to any one

of claim 1.

21. (Withdrawn) A solar cell according to claim 19 having a sequentially layered construction

comprising either one of a substrate on which an electrode layer is provided and a conductive

metal substrate, and further comprising a light absorbing layer of a p-type semiconductor

provided on said substrate, a middle layer of an n-type semiconductor provided on said light

absorbing layer, a window layer of a semiconductor provided on said middle layer, and an n-type

transparent electrode layer provided on said window layer, wherein said transparent electrode

layer is a transparent oxide electrode film having indium oxide containing titanium as its main

component, wherein indium in said indium oxide is substituted with titanium at a

titanium/indium atomic ratio between 0.003 and 0.120, said indium oxide is crystalline, and the

resistivity of said transparent oxide electrode film is up to  $5.7 \times 10^{-4} \Omega$ cm.

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22. (Withdrawn) A solar cell according to claim 20 having a sequentially layered construction

comprising a transparent electrode layer provided on a transparent substrate, a window layer of a

semiconductor provided on said transparent electrode layer, a middle layer of an n-type

semiconductor provided on said window layer, and a light absorbing layer of a p-type

semiconductor provided on said middle layer, wherein said transparent electrode layer is a

semiconductor provided on said initiatic tayer, wherein said transparent electrode tayer is a

transparent oxide electrode film having indium oxide containing titanium as its main component, wherein indium in said indium oxide is substituted with titanium at a titanium/indium atomic

ratio between 0.003 and 0.120, said indium oxide is crystalline, and the resistivity of said

transparent oxide electrode film is up to  $5.7 \times 10^{-4} \Omega$ cm.

23. (Withdrawn) A solar cell according to claim 21, wherein said light absorbing layer is at least

one member selected from the group of CuInSe2, CuInS2, CuGaSe2, CuGaS2 and a solid solution

of these compounds, and CdTe.

24. (Withdrawn) A solar cell according to claim 21, wherein said middle layer is either one of a

solution precipitated CdS layer and a (Cd, Zn) S layer.

25. (Withdrawn) A solar cell according to claim 21, wherein said window layer is either one of

ZnO and (Zn, Mg) O.

26. (Withdrawn) A photo detection element comprising a pair of electrodes and a layer of photo

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detection materials interposed between the said electrodes, wherein the transparent oxide

electrode film according to claim 1 is used as at least one of the said electrodes.

27. (Withdrawn) A photo detection element according to claim 26, wherein the said layer of

photo detection materials is a layer of infrared light detection materials and the photo detection

element is for detecting infrared light.